



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Clark Hu

Application No.: 10/045,412 (CONF 6396)

Filed: 1/12/2002

Title: Semiconductor wafer tilt monitoring on
semiconductor fabrication equipment plate

Attorney Docket No.: 67,200-655

Group Art Unit:
2877

Examiner:
Michael Patrica Stafira

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, Va 22313-1450

Date:

July 16/03


Kathy Dixon

RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office Action of April 16, 2003, please consider the following remarks. It is noted that the claims are presented in the suggested USPTO format, but that none have been amended or cancelled in this response.

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Response
for